Figure 1

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Start

Fabricate SOI Wafer	46
Etch Insulating Trenches	48
Fill Insulating Trenches	50
Remove Mask	52
Etch Backgate Trench	54
Fill Backgate Trench	56
Polish	58
Etch Channel	60
Fill Channel	62
Polish	64
Light Implant	66
Form Gate	67
Implant Source and Drain	68
Remove Gate Mask	69

Figure 2

70

74
72
76

Figure 3a

77
82
82
78   80   78
74
72
76

Figure 3b

78   80   78
74
72
76

Figure 3c

88
86
78 80   84   80 78
74
72
76

Figure 3d
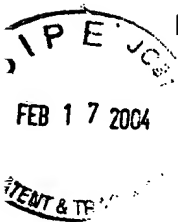
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Figure 3e

Figure 3f

Figure 3g

Figure 3h
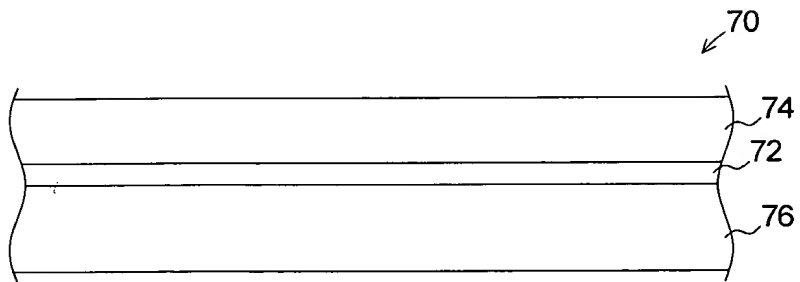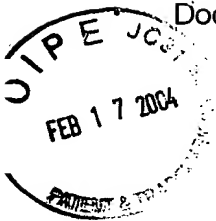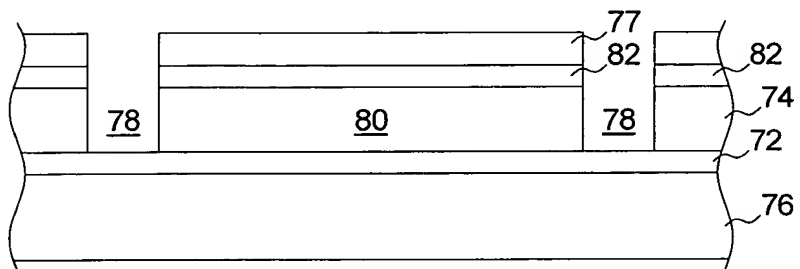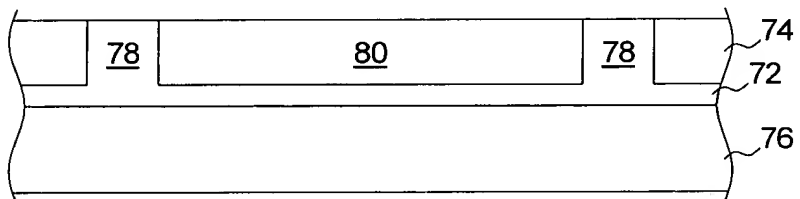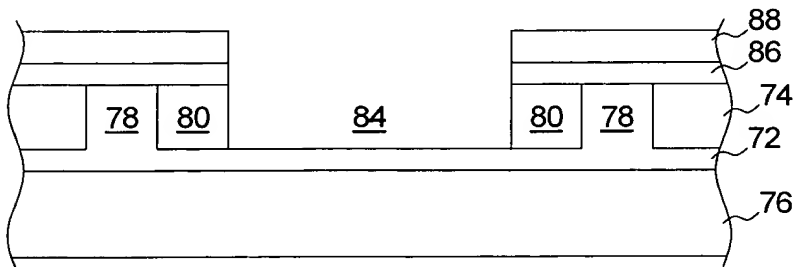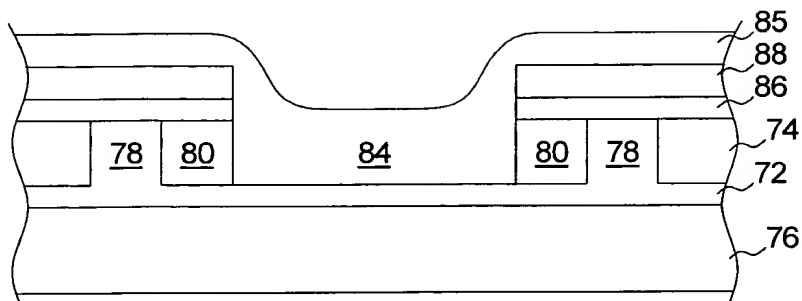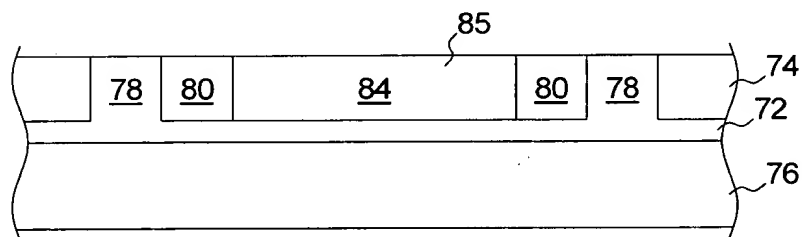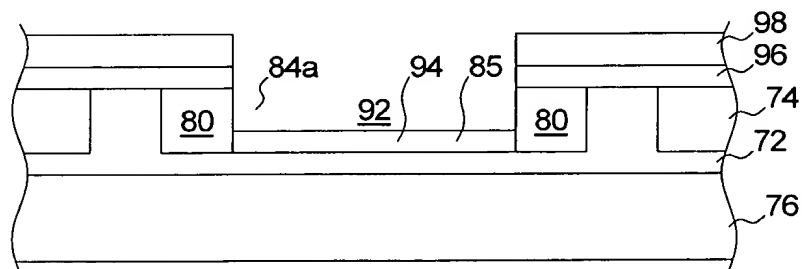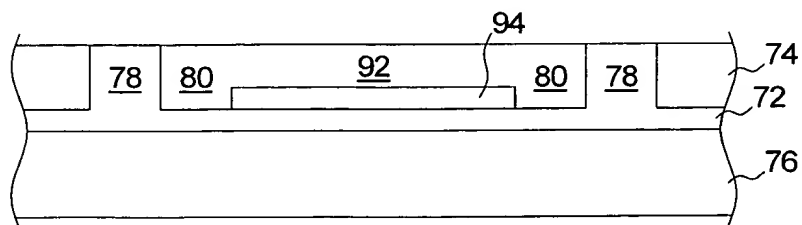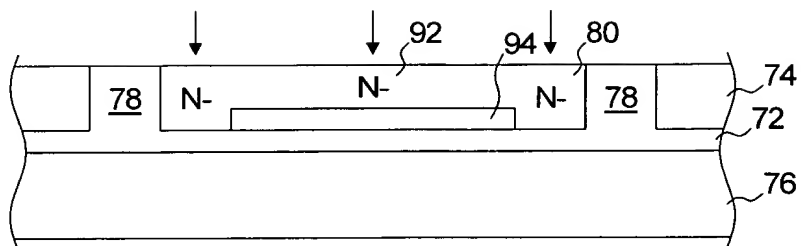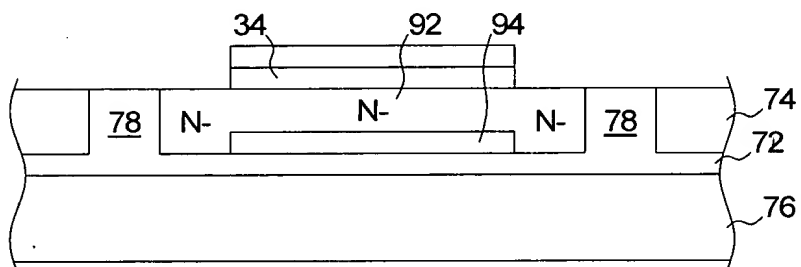
Figure 3i

Figure 3j

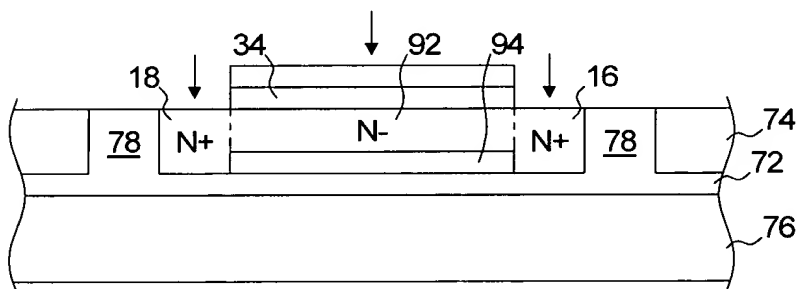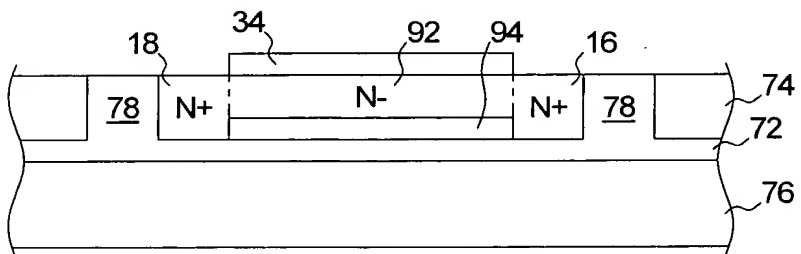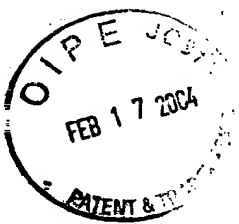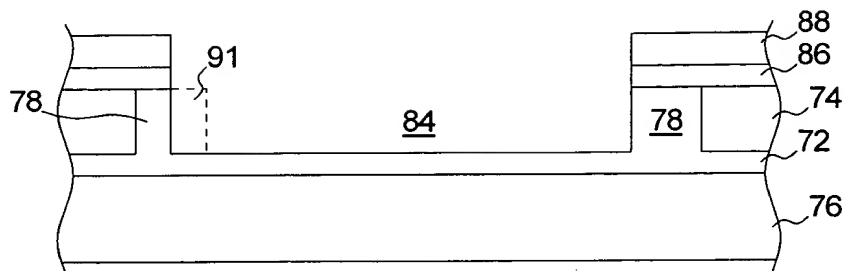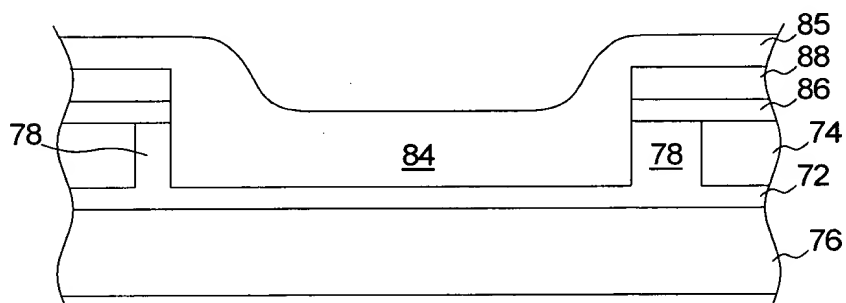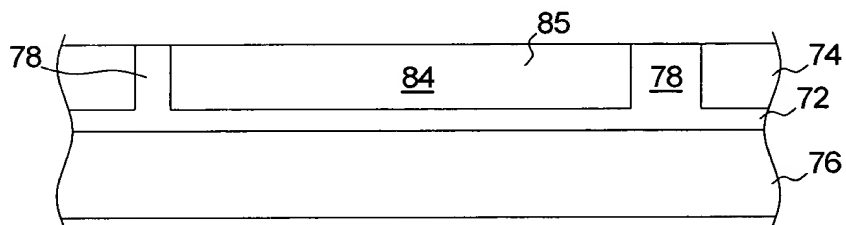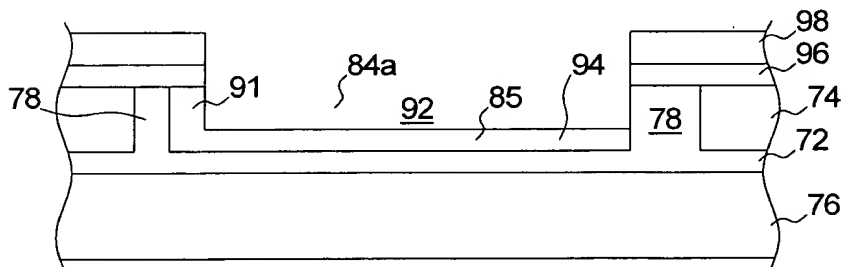Figure 3k

Figure 3l

Figure 4a

Figure 4b

Figure 4c

Figure 4d

Figure 4e

Figure 4f